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Facsimile Number: 703-872-9306	Transmission Date:	June 23, 2005

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant: Haupt Docket No.: INTECH 3.0-104 (2003 P  
 51718 US)  
 Serial No: 10/766,053 Art Unit: 2822  
 Date Filed: January 28, 2004  
 Title: Method for N+ Doping of Amorphous Silicon and Polysilicon Electrodes in  
 Deep Trenches

**CERTIFICATION OF FACSIMILE TRANSMISSION**

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- Petition for Extension of Time Under 37 CFR 1.136(a) (1 original and 1 copy)
- Election (2 pages)

Respectfully submitted,  
  
 Andie Marie James  
 Legal Assistant

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